# MOS - TRANSISTOR AS SWITCH

# **MOS-transistor as switch:**

#### Off resistance:

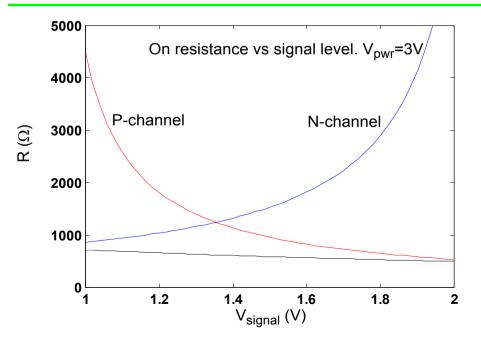
In the range 0.1-10 G $\Omega$  (Depends on technology and channel length).

#### On resistance:

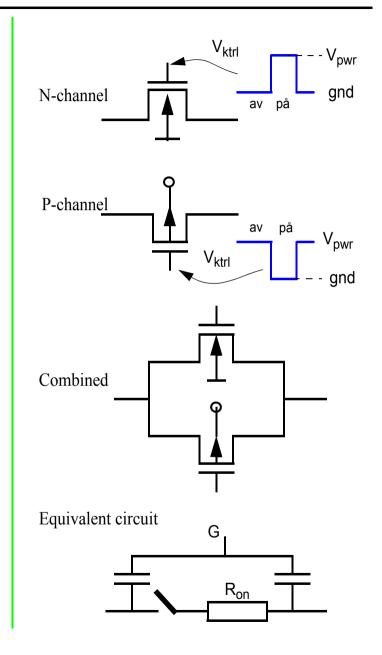
Applying the expression for Drain current when the transistor operates in the linear region:

$$R_{on} = \frac{1}{g_d} = \frac{1}{\mu C_{ox} \frac{W}{L} [V_{gs} - V_T - V_{ds}]}$$
(3.1)

Where  $V_{T} = V_{T0} + \gamma(\sqrt{|2\Phi_{F}| + V_{sb}} - \sqrt{|2\Phi_{F}|})$ 



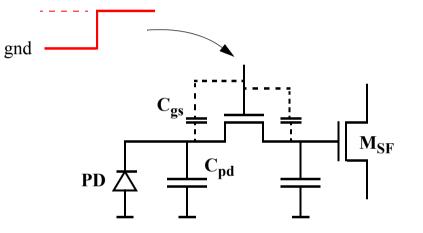




# **Clock Feed Through**

The control signal is coupled to the photo diode via a capacitive voltage divider:

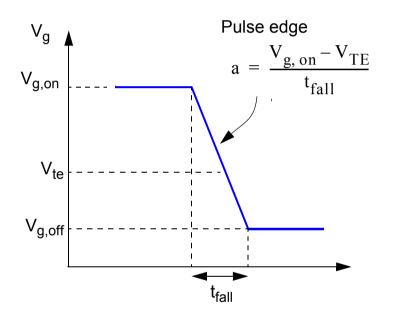
$$v_{pd} = v_{sign} \frac{C_{gs}}{C_{gs} + C_{pd}}$$
(3.2)



#### Charge injection in Source and Drain

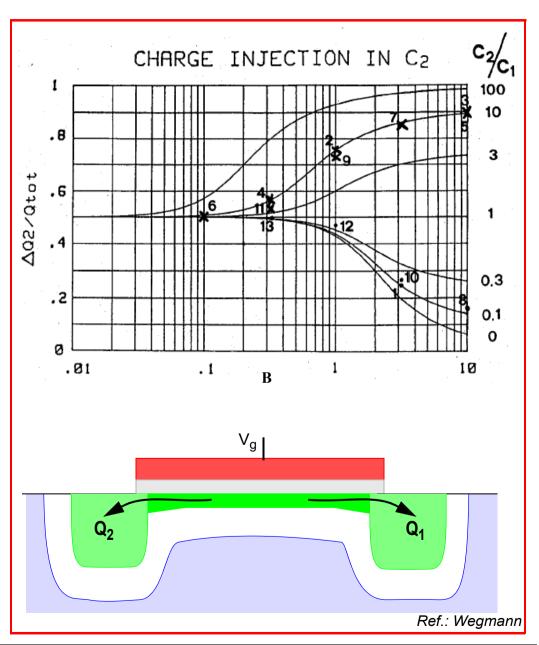
Extracts form:

Charge Injection in Analog MOS Switches George Wegmann, Eric A. Vittoz and Fouad Rahali. IEEE JSSC, vol. sc-22, no. 6, Dec 1987



B expresses the normalized Transistor length related to mobility and time:

$$B = (V_{g, on} - V_{TE}) \sqrt{\frac{\beta}{aC_2}}$$
$$\beta = \frac{W}{L} \mu C_{ox}$$



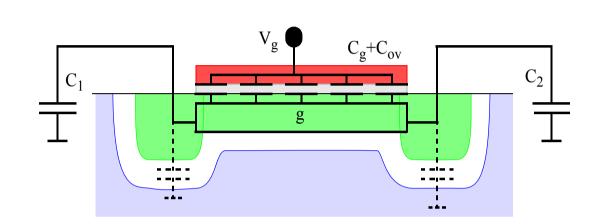
## Pixel Read Out

Effective threshold voltage (Wegmann):

$$V_{TE} = V_{T0} + \left(1 + \frac{\gamma}{\sqrt{\Phi_F}}\right) V_{in}$$

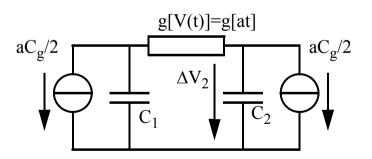
Conditions:

$$t_{fall} \gg T_{transit}$$
  
 $C_1, C_2 \gg G_g$ 



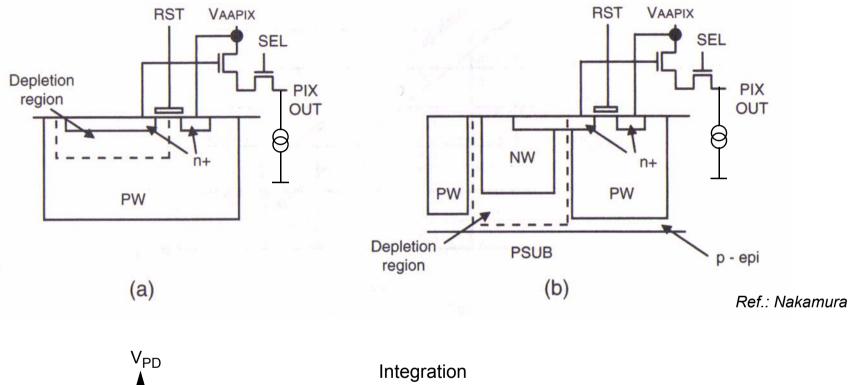
Consider the channel as a voltage controlled conductance:

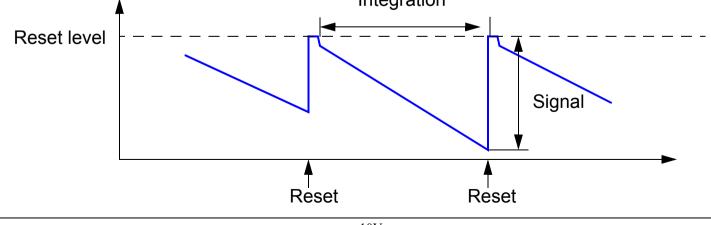
$$g[V_g(t)] = \beta(V_g(t) - V_{TE})$$
$$= \beta(V_{g, on} - at - V_{TE})$$



# PIXEL READ OUT

## 3T - pixel





## Pixel Read Out

## Soft reset

The N-channel transistor does not completely reset the diode to V<sub>aa</sub>.

Current in a saturated transistor:

$$I_{d} = \frac{\mu C_{ox} W}{2} [V_{gs} - V_{T}]^{2}$$
(3.3)

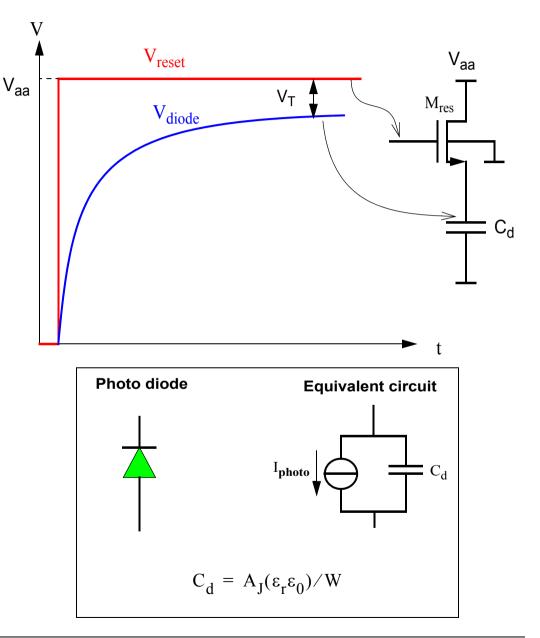
The transistor threshold voltage increases with the voltage across the diode due to the body effect:

$$V_{T} = V_{T0} + \gamma(\sqrt{|2\Phi_{F}| + V_{sb}} - \sqrt{|2\Phi_{F}|})$$
 (3.4)

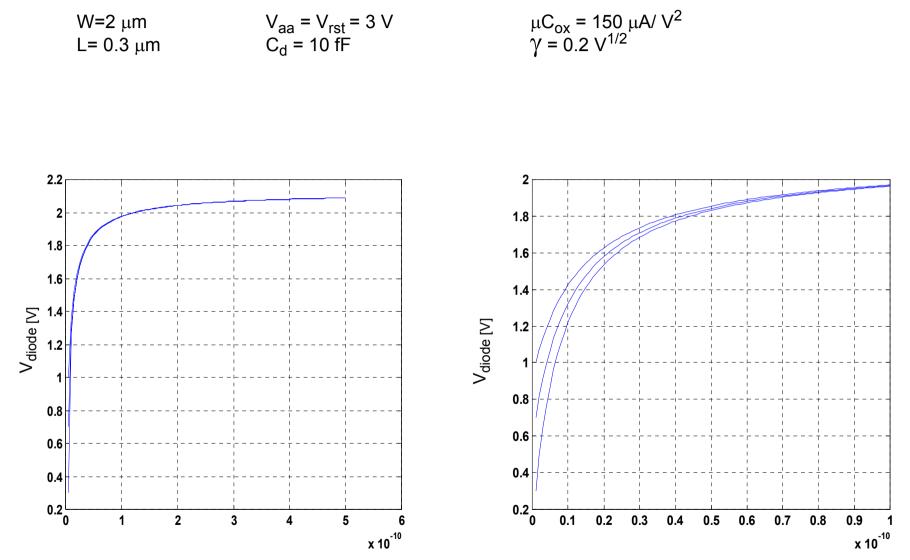
By connection the maximum voltage ( $V_{aa}$ ) to the gate,  $V_{gs} = V_{ds}$ , the transistor will always be saturated

$$V_{ds} > V_{ds,sat} = V_{gs} - V_T$$

but it will go into weak inversion and finally completely pinch off.



### Simulated example:



# Lag

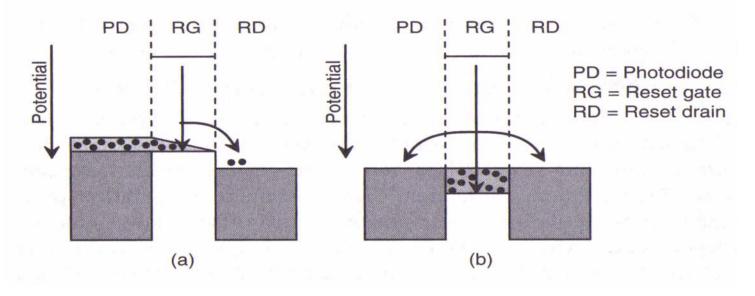
Final reset level at the end of the reset period, depends on the signal level at the beginning of the reset period. There will be some remaining charge in the photo diode. In other words, The image will contain remains from the previous image.

#### Methods to avoid lag:

Flushing: To charge the pixel completely before reset to make sure the start conditions are always the same, the remaining charge is always the same.

Hard reset: To make sure that the reset transistor does not pinch off, and the pixel is completely reset to V<sub>aa</sub>.

- P-channel transistor. Draw back: Larger area due to the required N-well.
- Boosting the control signal V<sub>reset</sub>. To generate a control signal with higher voltage than the power supply.



## Boosting

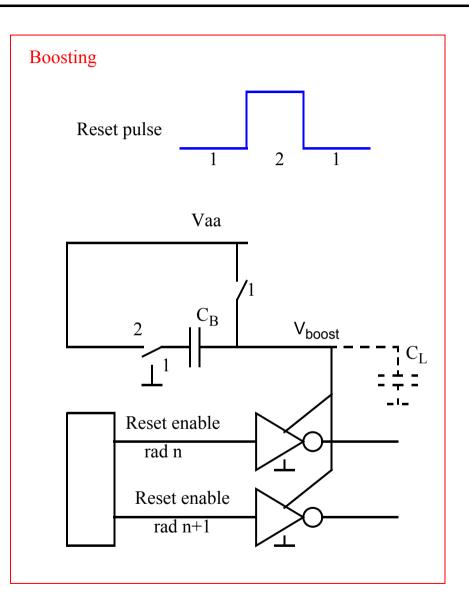
Phase 1:

 $C_{B}$  and  $C_{L}$  are charged to  $V_{aa}$ 

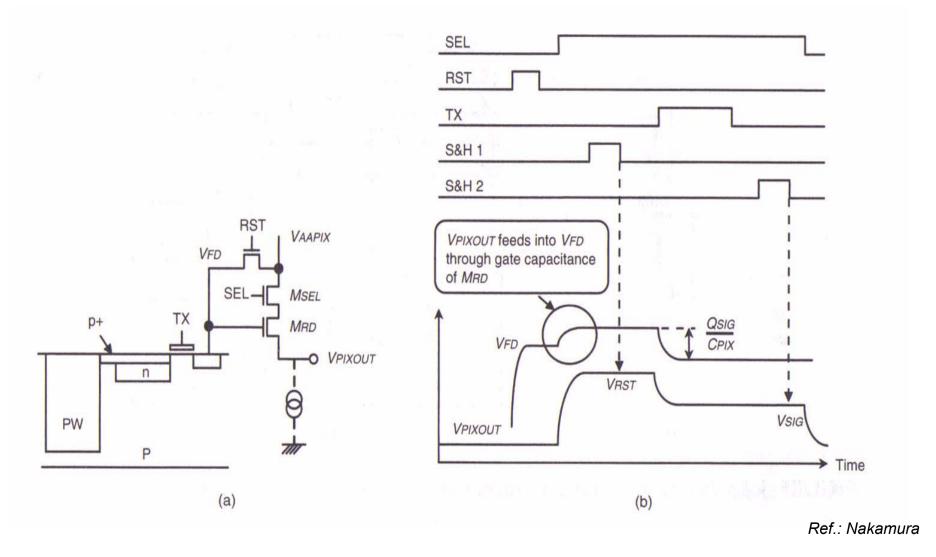
Phase 2:

Signal voltage is raised to

 $V_{boost} = V_{aa} + V_{aa}^* C_B / (C_L + C_B)$ 



# Alternative boosting



## **Pinned Photo diode**

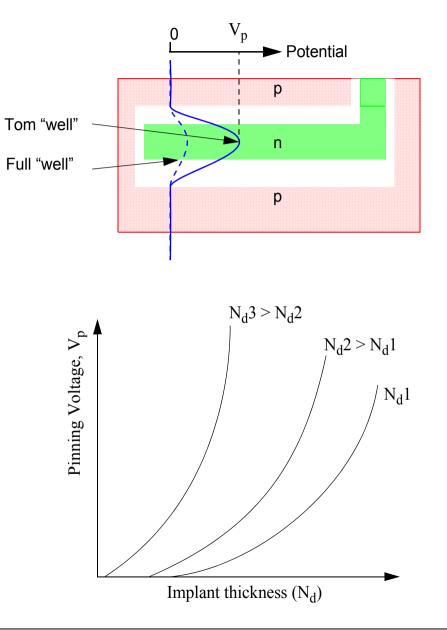
n-region buried in a p-substrate. Reduces the effect of surface recombination

- Improved response in blue range
- Reduced dark current.

Pinned voltage = the voltage that results in a complete depletion of the n-region.

Pinning voltage depends on doping concentration and implantation range.

Added process step to standard CMOS process. Patented: Eastman-Kodak/Motorola (ImageMOS<sup>TM</sup>).



## **Noise Sampling**

The signal that represents integrated light:

$$V_{\text{signal}} = V(t_{\text{reset}}) - V(t_{\text{int}})$$
 (3.5)

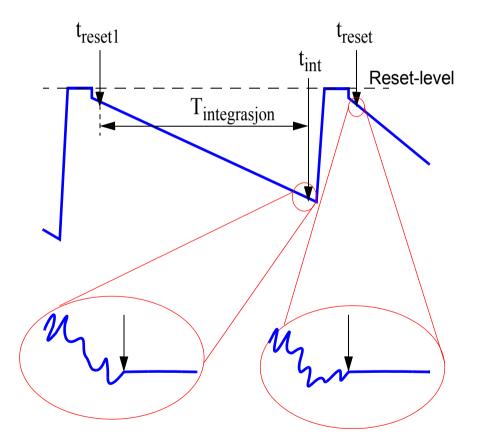
Noise sampled at the two time points are uncorrelated and contribute to the signal noise:

$$v_{n, rms} = \sqrt{[v_n(t_{reset})]^2 + [v_n(t_{int})]^2}$$
 (3.6)

The noise sampled at point t  $_{resert1}$  is correlated with the noise at  $t_{int}$ , but it cannot be used because it is not practical to store all pixel reset samples on capacitors during the exposure time.

However, the Fixed Pattern Noise due to variations in signal offset from pixel to pixel is removed.

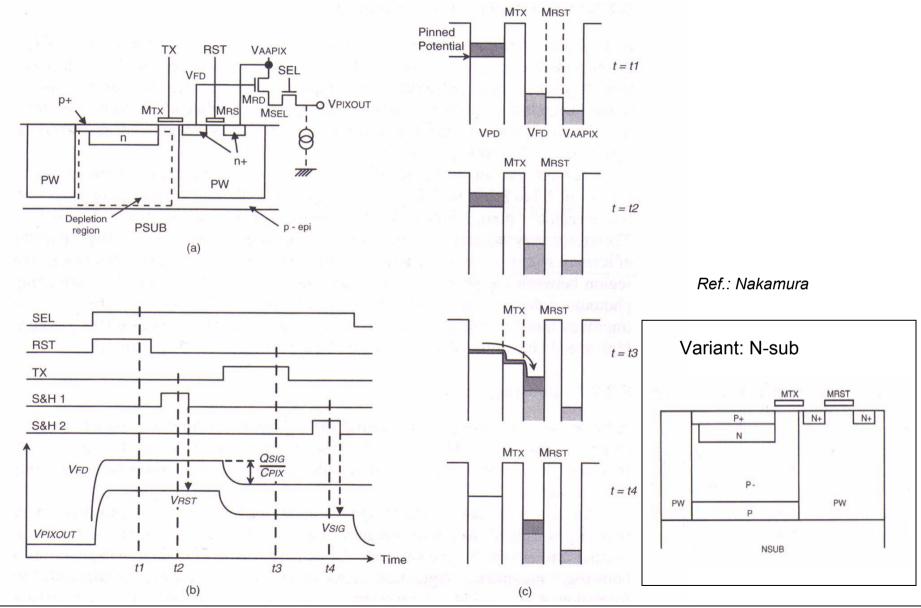
- Reset level variations
- Threshold voltage variations in the SF transistor



AO

## **Pixel Read Out**

#### 4T - Pixel

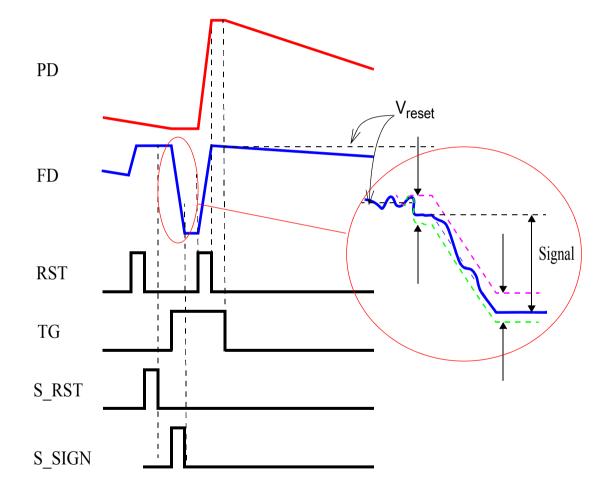


## 4T - pixel (forts.)

#### **Correlated Double sampling**

Both the Reset sample and signal sample after the charge transfer are related to the same reset voltage. No intermediate reset is performed.

Thus the difference  $V_{reset} - V_{signal}$  is independent on the noise from reset voltage source sampled on FD during the reset process. The reset noise cancels out.



## **4T Pixel - Summary**

The generated charge stored on PD (Photo diode) during the integration is transferred completely to FD (Floating Diffusion) immediately after FD reset.

The signal is made up by the difference between the reset level and the level after integration:

V<sub>reset</sub> - Q<sub>Transferred</sub> / C<sub>FD</sub>.

Pinning voltage, TX pulse height, and the capacity of FD is chosen such that complete transfer is achieved.

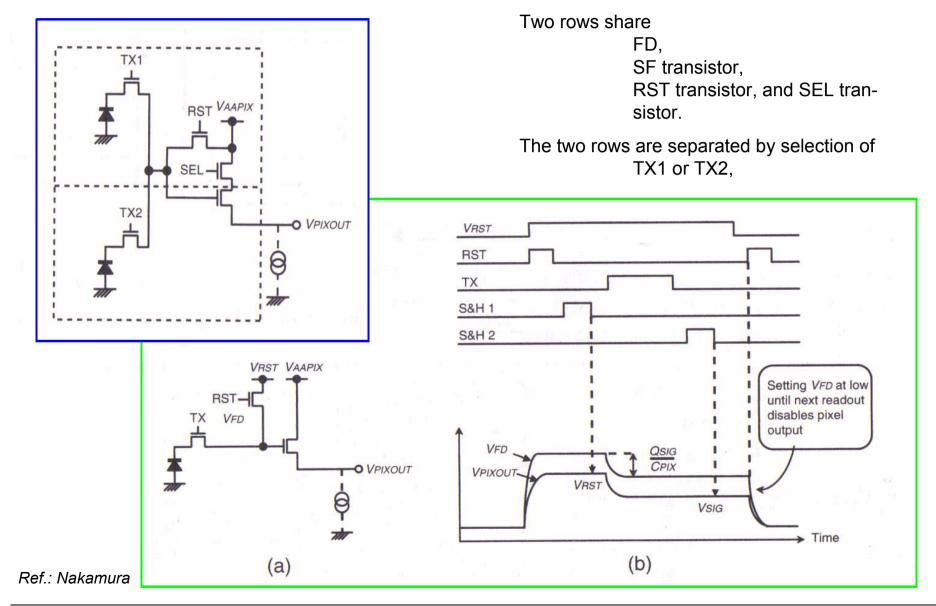
Advantages:

- High conversion gain given by FD
- Large light sensitive area.
- · High sensitivity to blue light.
- Low dark current
- Correlated double sampling reduces sampling noise.

Low threshold voltage for the TX-transistor is required.

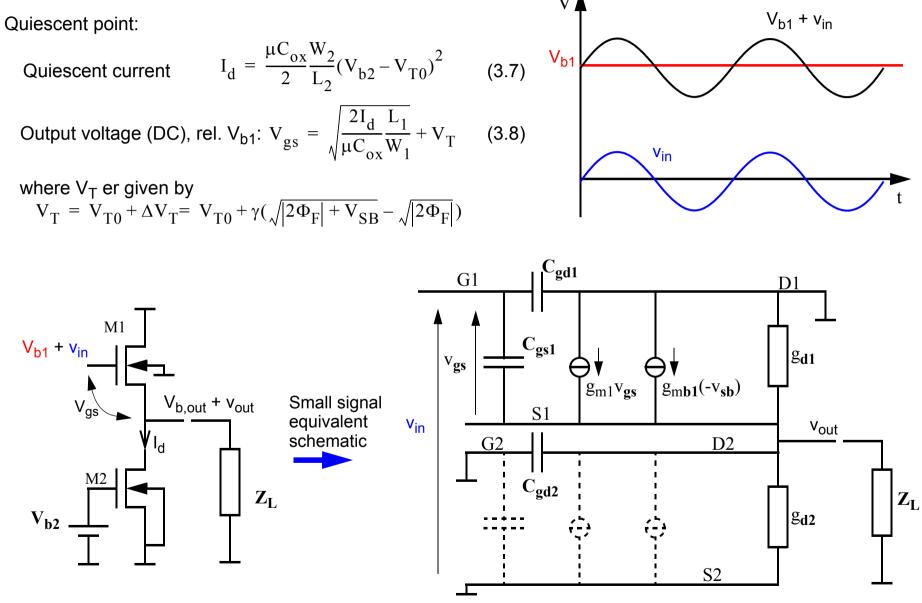
Complete charge transfer is prerequisite for low noise (zero sampling noise).

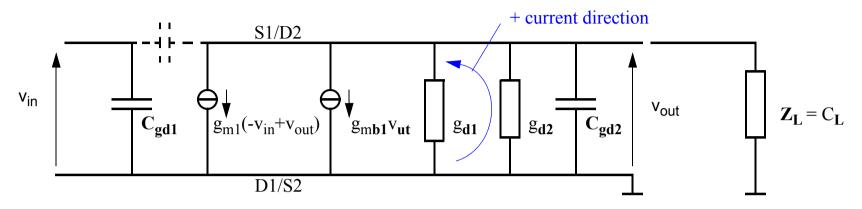




# SOURCE FOLLOWER AMPLIFIER STAGE

## **Source follower**





The pixel read-out circuit's output impedance,  $Z_L$ , is typically capacitive ( $C_L$ ). The time constant related to the output and upper cut off frequency  $f_h$  is:

$$\tau_{\rm h} = \frac{C_{\rm gd2} + C_{\rm L}}{g_{\rm d1} + g_{\rm d2}} \implies f_{\rm h} = \frac{\omega_{\rm h}}{2\pi} = \frac{1}{2\pi\tau_{\rm h}}$$
 (3.9)

For f << f<sub>h</sub>:

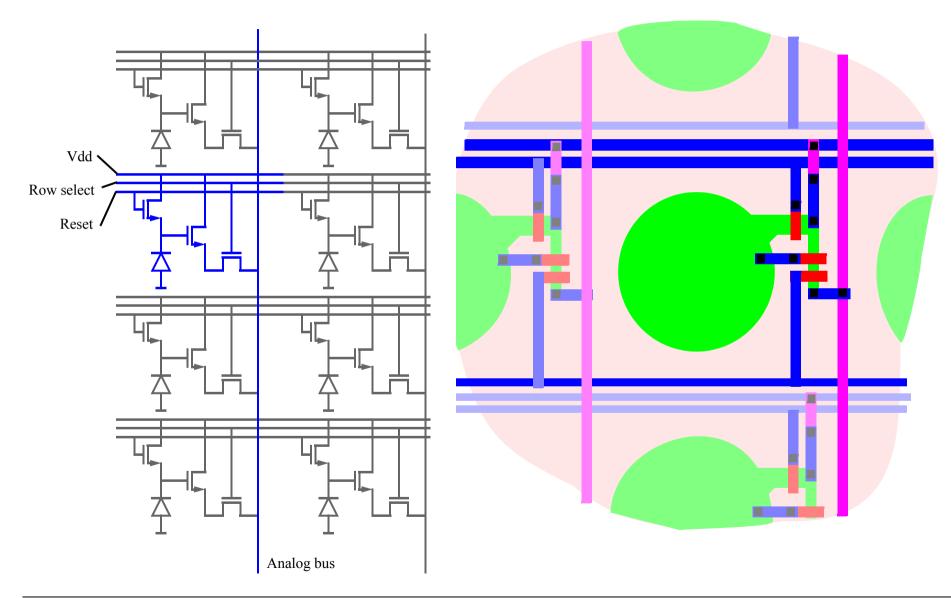
$$v_{ut} = \frac{g_{m1}v_{in} - g_{m1}v_{out} - g_{mb1}v_{out}}{g_{d1} + g_{d2}}$$
(3.10)

Gives the amplification:

$$\frac{v_{ut}}{v_{inn}} = \frac{g_{m1}}{g_{m1} + g_{mb1} + g_{d1} + g_{d2}} \approx \frac{g_{m1}}{g_{m1} + g_{mb1}} < 1, \quad \text{typically 0.7-0.8}$$
(3.11)

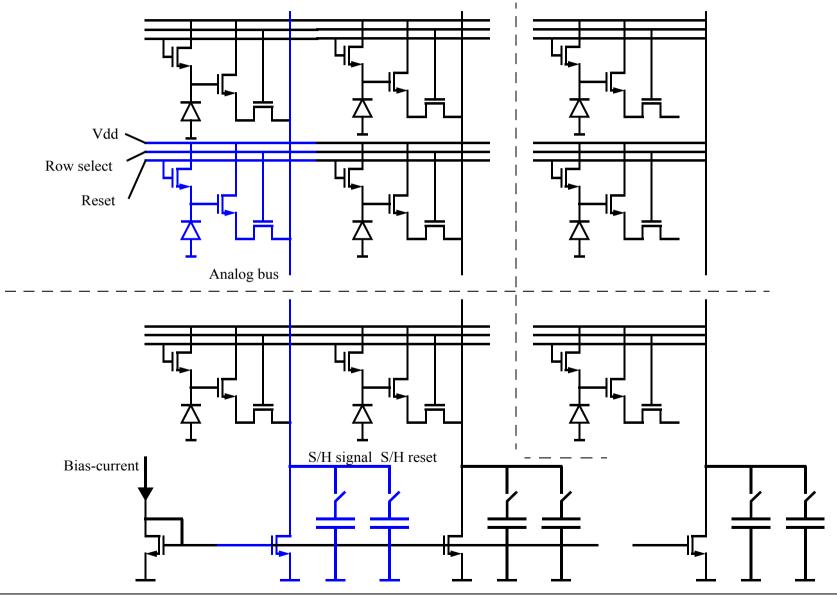
## **Pixel Read Out**

# **Pixel Array**

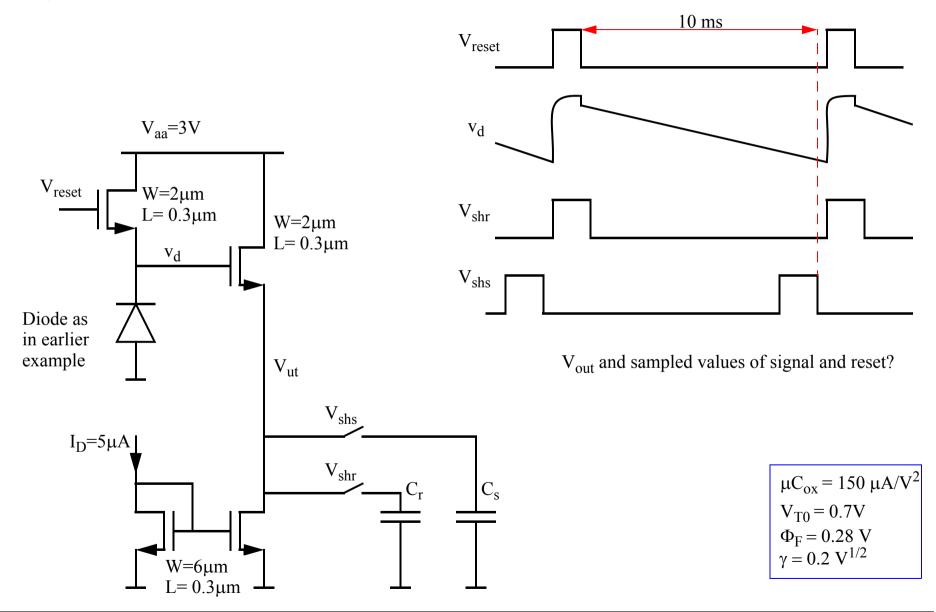


## **Pixel Read Out**

#### Pixel Array (cont.)



#### Example - Source Follower



# APPENDIX 1: MOS TRANSISTOR MODEL

## Appendix: MOS Transistor

## **MOS-structure**

(Metal Oxide Semiconductor)

The contact potential\*  $\Phi_{ms},$  forms a depletion range at the Silicon surface (Similar to a PN junction).

- Majority carriers are depleted away from the surface.
- Gives band bending.
- At equilibrium, the distance between the conduction band E<sub>c</sub> and the Fermi level is large. Therefore the carrier concentration in the conduction band is low.

Band bending:

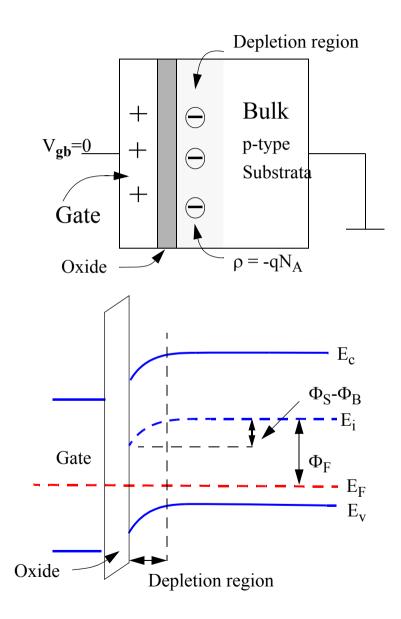
$$\Phi_{\rm S} - \Phi_{\rm B} = \frac{E_{\rm i} \text{ at the interface} - E_{\rm i} \text{ in bulk}}{q}$$

Potential difference between intrinsic Fermi level  $E_i$  and the actual Fermi level  $E_F$ :

$$\Phi_{\rm F} = \frac{{\rm E}_{\rm i} - {\rm E}_{\rm F}}{\rm q}$$

Band bending is changed by external voltage at the Gate. The system is then no longer in equilibration.

\* Contact potential = the difference in electron escape energy divided by its charge q.



## **Positive Bias Voltage at the Gate**

By increasing the band bending the distance  $E_c - E_F$  at the interface is reduced, and the minority carrier concentration increases.

When the total band bending corresponds to 2x the difference  $E_i$ - $E_F$ , we have by definition strong inversion:

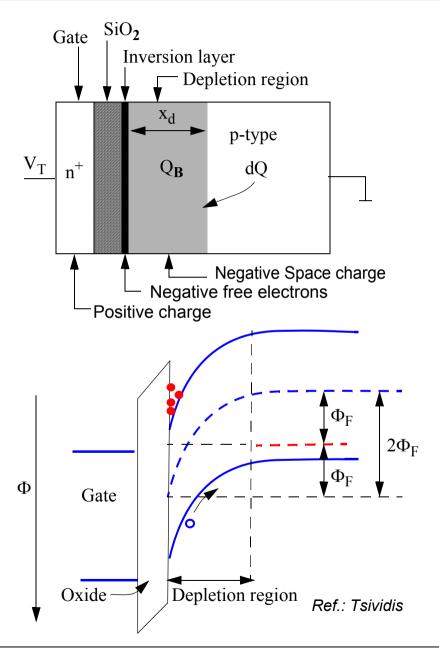
$$\Phi_{\rm S} - \Phi_{\rm B} = 2\Phi_{\rm F}$$

Where  $\Phi_S$  is the semiconductor surface potential and  $\Phi_B$  is the bulk potential.

The electron density is then high compared to the dopant concentration and becomes the majority carriers, that is, a p-type semiconductor is inverted to a n-type close to the  $Si/SiO_2$  interface. Similarly, a n-type is inverted to a p-type by adding a negative voltage on the Gate.

If the potential or band bending is further increased, only a small amount of space charges are uncovered. That is, a small increase of the depletion region, the charge is mainly added by generation of electrons. Thus, it is the inversion layer that constitute the charge contribution to the capacitor with oxide as dielectric.

The threshold voltage is defined as the voltage V<sub>GB</sub> required to bring the surface just into strong inversion:  $\Phi_S=2\Phi_F$ .



## Appendix: MOS Transistor

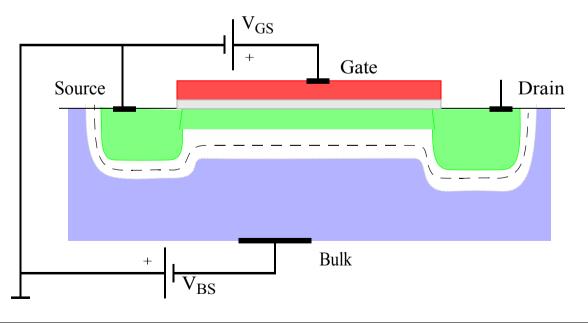
On a transistor with 4 terminals, the threshold voltage is the Gate-Source voltage,  $V_{GS}$ , that gives strong inversion. If the Source voltage is connected to Bulk (grounded),  $V_{T0}$  is the threshold voltage at  $V_B=0$ . The inversion layer forms a conduction channel underneath the gate between the Source and Drain regions.

Source-Bulk voltage,  $V_{BS}$ , changes the band bending and the charge  $Q_B$  in the depletion region (Source has contact to the channel).

The resulting threshold voltage can be written:

$$V_{T} = V_{T0} + \Delta V_{T} = V_{T0} + \gamma (\sqrt{|2\Phi_{F}| + V_{SB}} - \sqrt{|2\Phi_{F}|})$$

$$\gamma = \frac{\sqrt{2qN_{A}\varepsilon_{si}\varepsilon_{0}}}{C_{ox}}$$
(3.A1)



# Drain current in the linear region

 $V_{ds} < V_{GS} - V_T$ 

The channel has a given resistivity. The current creates a voltage variation v(y) along the channel. A voltage higher than the threshold gives charge in the inversion layer.

Inversion layer charge:

$$Q_{I}(y) = -C_{ox}[v(y) - (V_{GS} - V_{T})]$$

Current in the channel of width W:

$$I_D = WQ_I(y)\mu E = WQ_I(y)\mu \frac{dv}{dy}$$

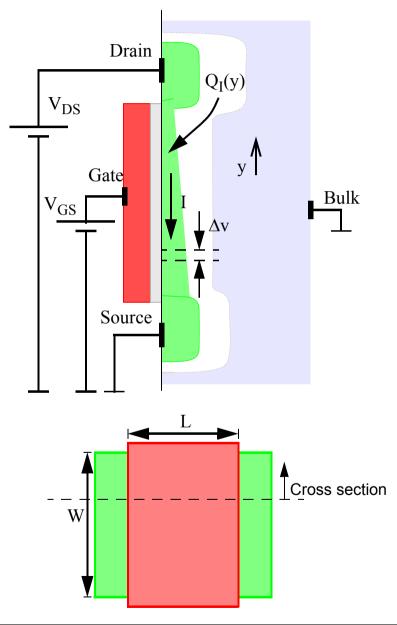
 $\mu$  is the carrier mobility typically:

 $\mu_n$ = 135  $\mu$ m<sup>2</sup>/(V.ns),  $\mu_p$ = 50  $\mu$ m<sup>2</sup>/(V.ns)

A change of variables and integration on both sides of the equation above gives:

$$Q_{I}(y) = Q_{I}(v(y))$$
  $v(y)|_{y=0} = 0$   $v(y)|_{y=L} = V_{DS}$ 

$$\int_{0}^{L} I_{D} dy = W \mu C_{ox} \int_{0}^{V_{DS}} [V_{GS} - v - V_{T}] dv$$
$$I_{D} = \mu C_{ox} \frac{W}{L} \left[ V_{GS} - V_{T} - \frac{1}{2} V_{DS} \right] V_{DS}$$
(3.A2)



# Drain current in saturated transistor

 $V_{ds} > V_{GS} - V_T$ 

Charge concentration in the inversion layer at the pinch-off point must be zero:

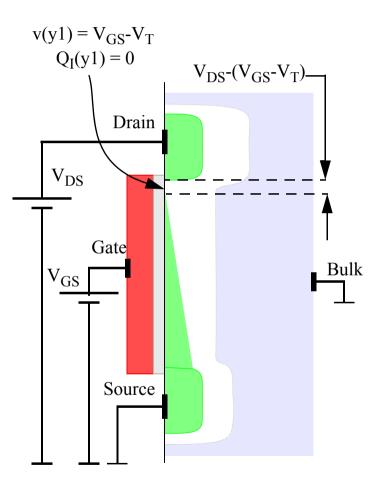
$$Q_{I}(y1) = C_{ox}[V_{GS} - v(y1) - V_{T}] = 0$$
  
$$C_{ox}[V_{GS} - (V_{GS} - V_{T}) - V_{T}] = 0$$

We see that v(y1) must be equal to  $V_{GS}$ - $V_T$ .

When V<sub>DS</sub> increases beyond V<sub>GS</sub>-V<sub>T</sub>, the voltage increase appear between Drain and the pinch-off point; an increase in the field in that region. The potential difference between source and the pinch off point becomes V<sub>GS</sub>-V<sub>T</sub> (Source is grounded) and is independent on V<sub>DS</sub>.

Replacing  $V_{DS}$  with  $V_{GS}$  - $V_T$  inn i (3.A2):

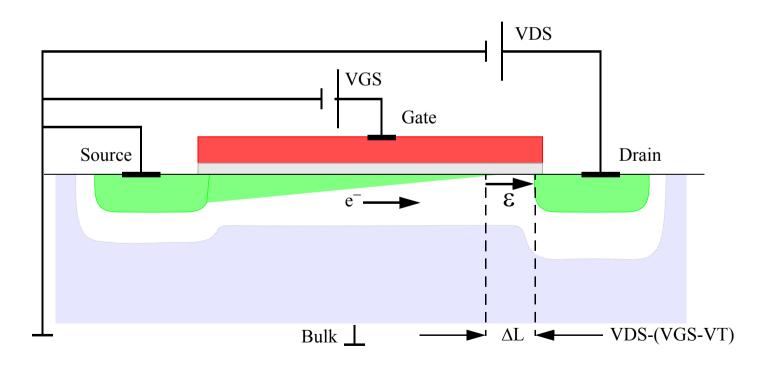
$$I_{d} = \frac{\mu C_{ox}}{2} \frac{W}{L} [V_{GS} - V_{T}]^{2}$$
(3.A3)



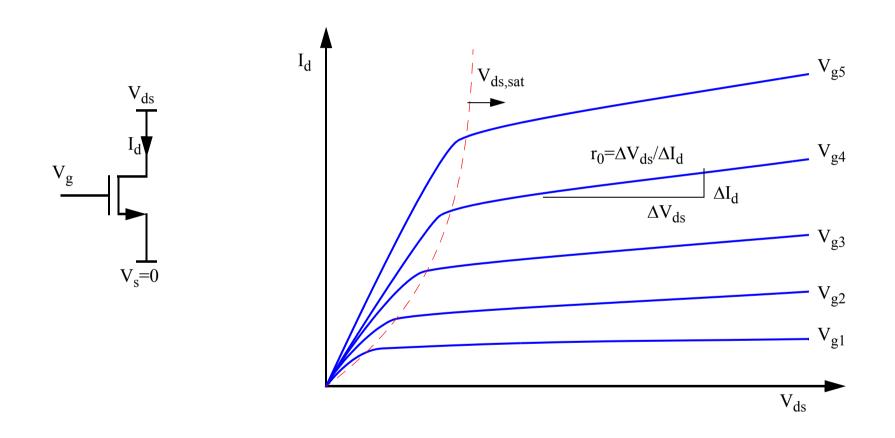
## Channel length modulation.

In saturation, the channel length is shortened with increasing  $V_{DS}$ . The shortening increases the current because the current is limited by diffusion in the inversion layer along the channel, not by the field across the region between Drain and Pinch off point. The carriers are driven fast across this region. The effect is important for short channels.

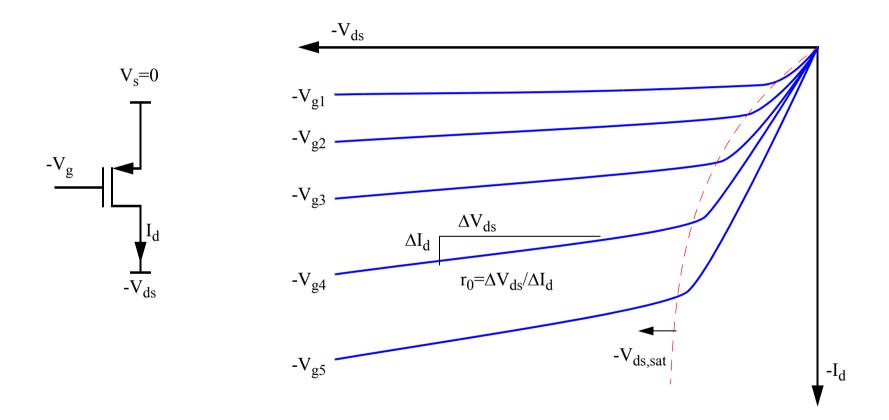
$$I_{d} = \frac{\mu C_{ox}}{2} \frac{W}{L} [V_{GS} - V_{T}]^{2} (1 + \lambda V_{DS})$$
(3.A4)



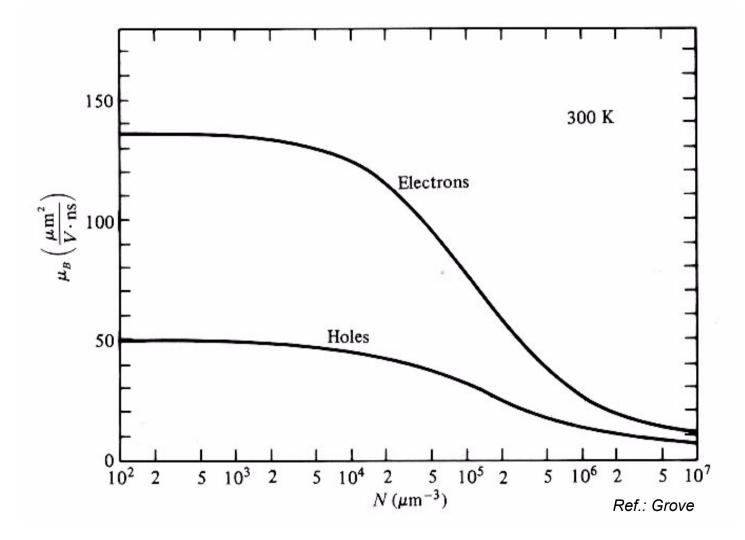
# **Output characteristics for NMOS**



## **Output characteristics for PMOS**t



## Mobility as a function of doping concentration



### Small signal parameters:

Transconductans at constant  $V_{SB}$ ,  $V_{DS} > V_{GS} - V_T$ . (Differentiate (3.A3))

$$g_{\rm m} = \frac{dI_{\rm d}}{dV_{\rm gs}} = 2\frac{\mu C_{\rm ox}}{2}\frac{W}{L}[V_{\rm gs} - V_{\rm T}] = \sqrt{\left(2\mu C_{\rm ox}\frac{W}{L}\right)\left(\frac{\mu C_{\rm ox}}{2}\frac{W}{L}\right)\left[V_{\rm gs} - V_{\rm T}\right]^2} = \sqrt{2\mu C_{\rm ox}\frac{W}{L}I_{\rm D}}$$
(3.A5)

Bulk transconductans at constant  $V_{GS}$ ,  $V_{DS} > V_{GS} - V_T$  (Differentiate (3.A3) with  $V_T$  given by (3.A1))

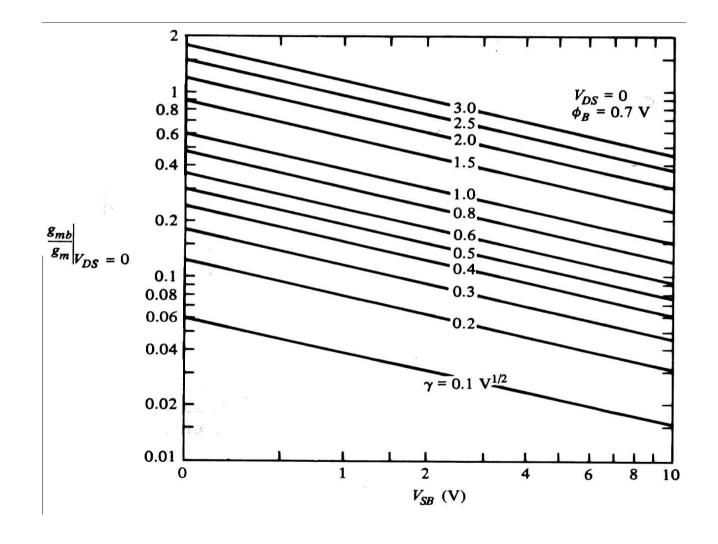
$$g_{mb} = \frac{dI_{d}}{dV_{sb}} = \frac{dI}{dV_{T}} \frac{dV_{T}}{dV_{sb}} = 2\frac{\mu C_{ox}}{2} \frac{W}{L} [V_{gs} - V_{T}] \frac{\gamma}{\sqrt{|2\Phi_{F}| + V_{sb}}} = \frac{\gamma gm}{\sqrt{|2\Phi_{F}| + V_{sb}}}$$
(3.A6)

Output conductance (differentiate (3.A2) and (3.A4)

$$g_{d} = \frac{dI_{d}}{dV_{ds}} = \mu C_{ox} \frac{W}{L} [V_{gs} - V_{T} - V_{ds}] \qquad V_{ds} < V_{gs} - V_{T}$$
 (3.A7)

$$g_{d} = \frac{dI_{d}}{dV_{ds}} = \frac{\lambda I_{DS}}{(1 + \lambda V_{DS})} \approx \lambda I_{DS} \qquad V_{ds} \ge V_{gs} - V_{T} \qquad (3.A8)$$

# The ratio $g_{mb}$ to $g_m$





## Capacitance

For  $V_{ds} < V_{gs} - V_T$ :

$$C_{gc} = C_{ox}WL + 2C_{ovl}W$$
(3.A9)

$$C_{cb} = \frac{\varepsilon_{si}}{x_d} WL$$
 (3.A10)

For 
$$V_{ds} > V_{gs} - V_T$$
:  

$$C_{gs} = \frac{2}{3}C_{ox}WL + C_{ovl}W \quad \text{(empiric)} \quad (3.A11)$$

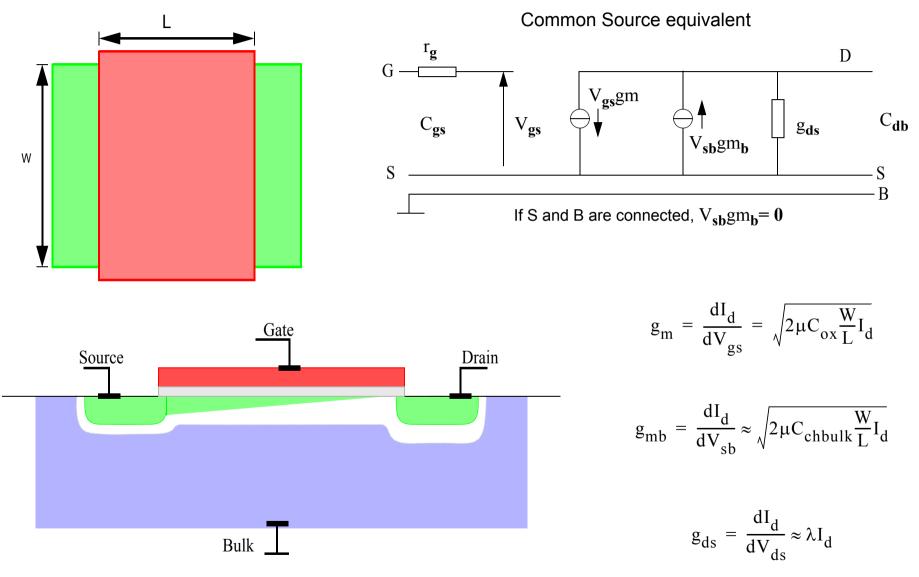
$$C_{gd} = C_{ovl} W$$
 (3.A12)

Source - Drain junction capacitance (used in SPICE level=3):

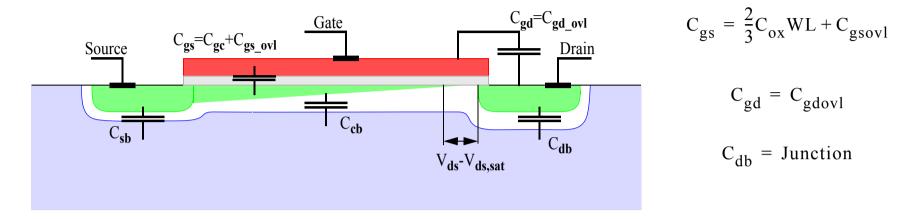
$$C_{j} = A \cdot CJ \left[ 1 - \frac{V_{j}}{PB} \right]^{-MJ} + P \cdot CJSW \left[ 1 - \frac{V_{j}}{PB} \right]^{-MJSW}$$
(3.A13)

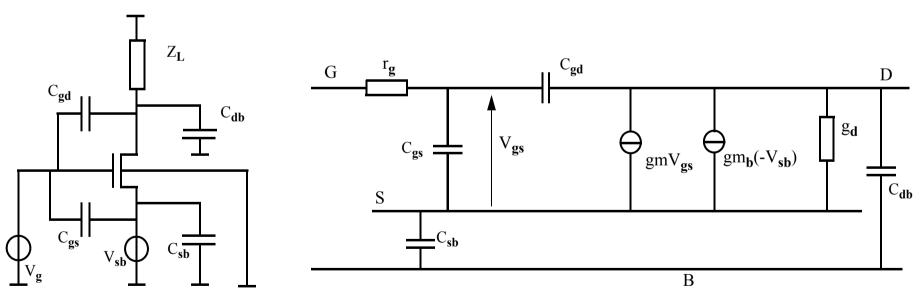
A= area, P=perimeter

## Small signal equivalent



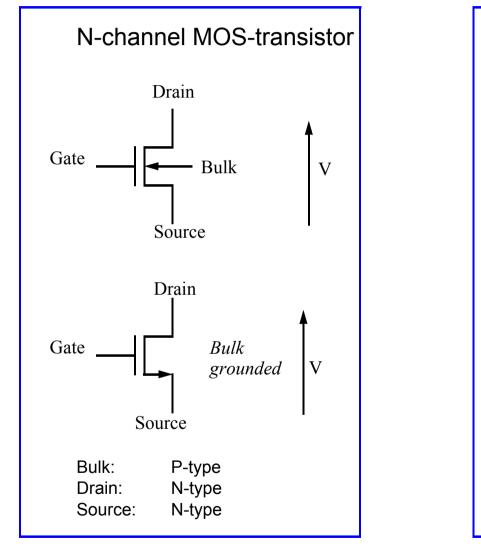
## Small signal equivalent (cont.)

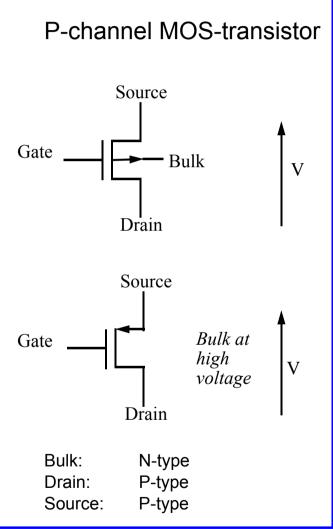




 $V_{gs} = V_g - V_{sb}$ 

## **Transistor symbols**





### **Diode connected transistor**

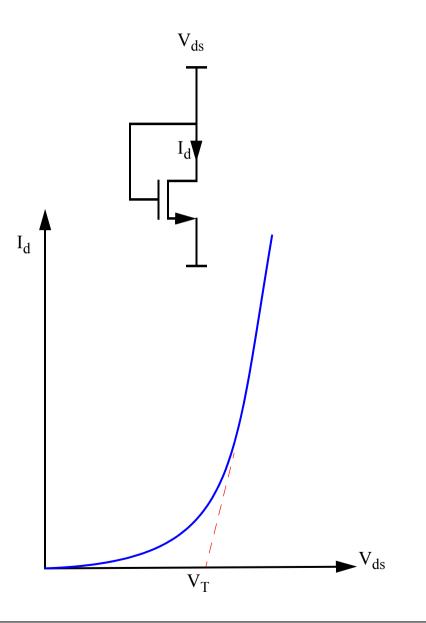
Given that the transistor is in strong inversion,

$$V_{GS} \ge V_T$$

it will always be saturated when V<sub>GS</sub>=V<sub>DS</sub> (connected) because the condition:  $V_{DS} \ge V_{GS} - V_T$  must be met

Input conductance:

$$g_{inn} \equiv \frac{dI_d}{dV_{ds}} = \frac{dI_d}{dV_{gs}} = g_m = \frac{1}{r_{inn}}$$
(3.A14)



## **Current mirrors**

- M1 is always saturated because V<sub>ds</sub> = V<sub>gs</sub> > V<sub>gs</sub> V<sub>T</sub>
- Assuming M2 saturated as well

Applying the expression for the drain current:

$$I_{d} = \frac{\mu_{0}C_{ox}}{2}\frac{W}{L}(V_{gs} - V_{T})^{2}(1 + \lambda V_{ds})$$

gives the output current:

$$I_{ut} = \frac{\frac{\mu_0 C_{ox} W_2}{2} (V_{gs} - V_T)^2 (1 + \lambda V_{ds2})}{\frac{\mu_0 C_{ox} W_1}{2} (V_{gs} - V_T)^2 (1 + \lambda V_{ds1})} I_{ref} = \frac{W_2 L_1 (1 + \lambda V_{ds2})}{L_2 W_1 (1 + \lambda V_{ds1})} I_{ref}$$
(3.A15)

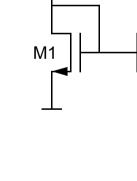
Ideally for long channels ( $\lambda$ =0), and when L<sub>1</sub>=L<sub>2</sub>:

$$I_{ut} = \frac{W_2}{W_1} I_{ref}$$



The simple expression above is inaccurate for short channels due to the final output resistance for M2. Therefore:

$$r_{ut} = \frac{1}{g_{M2}} = \frac{1}{\frac{dI_{d2}}{dV_{ds2}}} = \frac{1}{\frac{\mu_0 C_{ox} W}{2} (V_{gs} - V_T)^2 \lambda} = \frac{(1 + \lambda V_{ds})}{\lambda I_d} \approx \frac{1}{\lambda I_d}$$
(3.A16)



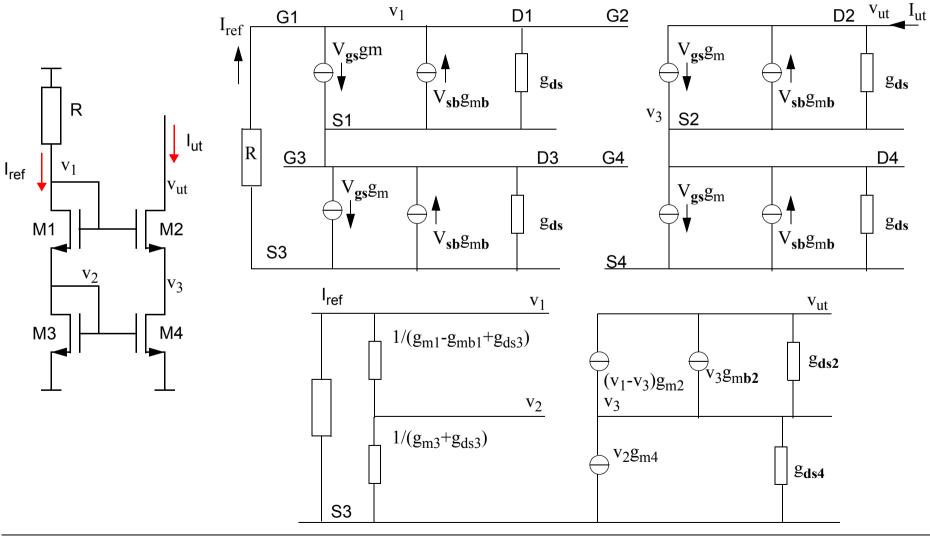
Iref

lut

M2

### **Cascoded current mirrors**

Have high output resistance



#### Output resistance $r_{ut} = dv_{ut} / di_{ut}$

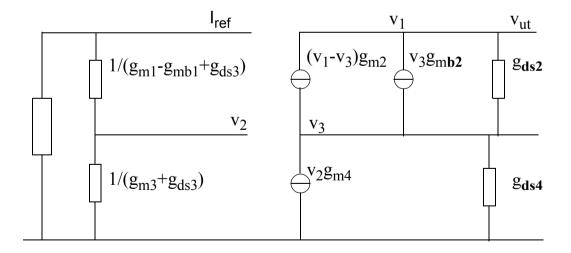
The DC voltages  $v_1 = v_2 = 0$  is zero in a small signal equivalent circuit:

$$i_{ut} - g_{m2}(v_1 - v_3) + g_{mb2}v_3 - g_{ds2}(v_{out} - v_3) = 0$$
 (a)

$$g_{ds4}v_3 + g_{m4}v_2 - g_{m2}(v_1 - v_3) + g_{ds2}(v_3 - v_{ut}) + g_{mb2}v_3 = 0$$
 (b)

Solving (b) for  $v_3$  and replacing  $v_3$  in (a). Reorganizing gives:

$$r_{ut} = \frac{v_{ut}}{i_{ut}} = \frac{g_{m2} + g_{mb2} + g_{ds2} + g_{ds4}}{g_{ds2}g_{ds4}} \approx \frac{g_{m2}}{g_{ds2}g_{ds4}} = \frac{g_{m2}}{g_{ds2}} \frac{1}{\lambda I_{ds}}$$
(3.A17)



# References

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